

^3He impurity effects on the growth kinetics of ^4He crystals

M. Suzuki*, M. Thiel, and P. Leiderer

Fakultät für Physik, Universität Konstanz, D-78434 Konstanz, Germany

We report on the growth kinetics of ^4He crystals with a small amount of ^3He impurities around 0.8K. The growth resistance was measured using the response of the charged liquid-solid interface with respect to an externally applied voltage. In 5ppm and 10ppm ^3He mixtures, it is found that (1) the relaxation process can be expressed as an exponential behavior, (2) the growth resistance becomes larger compared to pure ^4He and does not have a strong ^3He concentration dependence, and (3) the temperature dependence of the growth resistance is much the same as for pure ^4He . We discuss several possible explanations of the present experiment.

1. INTRODUCTION

From early visual observations it is known that adding a small amount of ^3He impurities drastically affects the shape of ^4He crystals. In 1992 Wang and Agnolet[1] found that at low temperatures a very small amount of ^3He impurities increases the growth resistance $(m_4 K_T)^{-1}$.

Regarding the crystal growth of dilute ^3He mixtures, Bowley and Edwards[2] discussed the effects on the basis of the idea that ^3He atoms are reflected at the solid-liquid interface. On the other hand, Buristrov and Dubovskii[3] pointed out the importance of ^3He mass flow in front of a moving solid-liquid interface.

In order to deduce the ^3He impurity effect quantitatively in the high temperature region, we measured the growth resistance using the response of a charged interface.

2. EXPERIMENTAL

The experiment was performed in a ^3He cryostat with optical access from the bottom. The sample cell worked as an interferometer and the change in crystal height was detected by a shift of the interference fringes. After growing the crystal, electron bubbles were introduced into the liquid by a field emission tip and pulled downwards to the solid-liquid interface by an externally applied field. These were trapped at the interface.

After changing the applied field, in the case where the crystal growth does not show nonlinear behavior, the height of the crystal approaches the new equilibrium exponentially. Then, the relaxation time is proportional to the growth resistance.

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Different dilute ^3He mixtures, 5ppm and 10ppm ^3He , were prepared at room temperature. A single crystal was grown slowly around 0.8K. Atomically rough surfaces were chosen for the measurement.

3. RESULTS AND DISCUSSION

Figure 1 shows the growth resistance of 10ppm of several measurements as a function of temperature as well as the extrapolated lines of pure ^4He (dashed lines) which are considered as the fastest and slowest axes of pure ^4He [4]. Without respect to temperature, the relaxation process can be well expressed as an exponential behavior.

Figure 2 shows the growth resistance at 0.83K as a function of the ^3He concentration. The scatter is attributed to crystal orientation.

From the present experiment, it is found that (1) the relaxation process can be expressed as an exponential behavior, (2) the growth resistance becomes larger compared to pure ^4He and does not have a strong ^3He concentration dependence, and (3) the temperature dependence of the growth resistance is much the same as for pure ^4He .

Next, let us consider several possibilities to explain these properties:

(a) the reflection of ^3He atoms at the solid-liquid interface: This contribution was evaluated by Bow-

*. Permanent address: Div. of Natural Sciences, Univ. of Electro-Communications, Chofu, Tokyo 182, Japan.

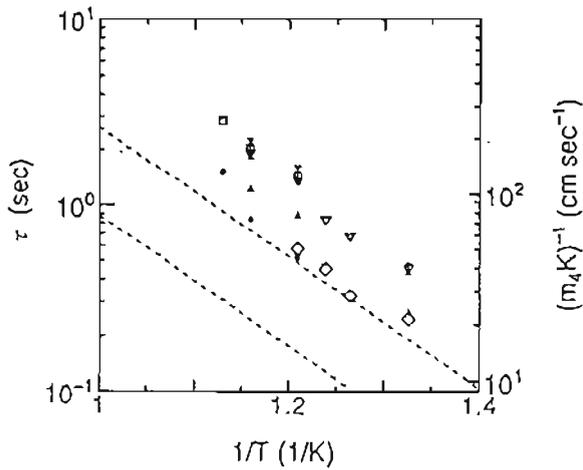


Figure 1: Temperature dependence of the growth resistance of a 10ppm ^3He mixture. Different symbols correspond to different crystals.

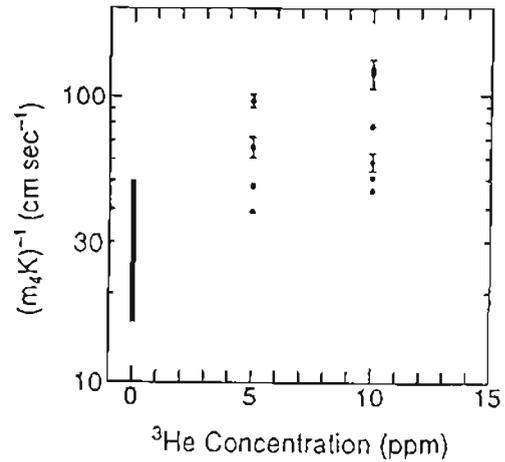


Figure 2: Concentration dependence of the growth resistance at 0.83K.

ley and Edwards[2]. Using the typical values of this experiment, we found that this contribution is too small.

(b) the ^3He mass flow in front of a moving interface: Buristov and Dubovskii's theory[3] explains the large enhancement of the growth resistance. There are, however, discrepancies between theory and experiment. Their theory suggests that the growth resistance depends strongly on ^3He concentration and that the relaxation process shows nonlinear behavior.

(c) the effect of adsorped ^3He atoms at the interface: The enhancement of the growth resistance may be explained by the change in the scattering potential of rotons associated with adsorped ^3He atoms. Rolley *et al.*[5] found that the binding energy of ^3He atoms at the interface is 4.3K. If we adopt their results, few ^3He atoms are adsorped at the interface (about 0.05 monolayer). So it may be difficult to explain the change in the growth kinetics.

(d) the effect of the decrease of the thermal conductivity in the liquid: As discussed in detail by Balibar *et al.*[6], the effective growth resistance $(m_4 K_e)^{-1}$ increases due to the finite thermal conductivity, which is given by

$$(m_4 K_e)^{-1} = (m_4 K_T)^{-1} + (\rho_c R_K / T)(J_E / J + b/c)^2, \quad (1)$$

where J and J_E/T are the currents of mass and entropy crossing the interface, R_K is the Kapitza resistance. Here, we use the same notation as used in Ref. 6.

In pure ^4He , the heat propagates very effectively in the superfluid ^4He and the correction to $(m_4 K_T)^{-1}$ is not large. On the other hand, the effective thermal conductivity in the liquid of dilute ^3He mixtures decreases drastically. Thus the main channel of heat flow seems to be the crystal rather than the superfluid ^3He - ^4He mixtures.

Using Eq.(1), we found that the effective growth resistance becomes about twice as large as that of pure ^4He and also shows much the same temperature dependence as pure ^4He .

In summary, it is found that a small amount of ^3He impurities affects the growth kinetics of ^4He crystals around 0.8K. The observed enhancement of the growth resistance may be attributable to the decrease of the effective thermal conductivity in dilute ^3He mixtures.

References

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